

What is claimed is:

1. A light-emitting diode comprising a light-emitting diode chip
mounted on a surface of a printed substrate, the light-emitting diode
5 chip including:

a substrate;

a semiconductor layer laminated on the substrate and formed of
an N-type semiconductor layer and a P-type semiconductor layer,
wherein its PN junction surface is perpendicular to the surface of the
10 printed substrate and a portion in the vicinity of the PN junction
surface is rendered to be a light-emitting portion;

a pair of electrodes for applying voltage to the semiconductor
layer; and

a light reflecting layer for reflecting light emitted from the
15 light-emitting portion,

wherein the light reflecting layer is formed on a front surface or a
back surface of the light-emitting diode chip or in the light-emitting
diode chip and is approximately parallel to the PN junction surface.

20 2. A light-emitting diode claimed in Claim 1, wherein the substrate
is made of a transparent substrate and the light reflecting layer is
formed on the front surface or back surface of the transparent substrate
or on the surface of the semiconductor layer.

3. A light-emitting diode claimed in Claim 2, wherein the light reflecting layer comprises a DBR diffraction grating structure formed on the surface of the transparent substrate.

Due AX2 5 4. A light-emitting diode claimed in Claim 1 or 2, wherein the light reflecting layer is formed of a metal thin film.

10 5. A light-emitting diode claimed in Claim 4, wherein the metal thin film is formed directly or via a dielectric thin film on the back surface of the transparent substrate.

Due AX3 6. A light-emitting diode claimed in Claim 4 or 5, wherein the metal thin film is formed of an Ni vapor-deposition film.

Due AX3 15 7. A light-emitting diode claimed in Claim 5, wherein the dielectric thin film is formed of an SiO₂ film or an Al₂O₃ film, and the metal thin film is formed of an AuBe vapor-deposition film or an Au vapor-deposition film.

Due AX4 20 8. A light-emitting diode claimed in any one of Claims 1 to 7, wherein the Ni vapor-deposition film has a thickness of 100 nm or more.

9. A light-emitting diode claimed in Claim 7, wherein the SiO₂ film

or the Al_2O_3 film has a thickness of approximately 3 to 60 nm, and the AuBe vapor-deposition film or the Au vapor-deposition film has a thickness of approximately 3 to 60 nm

5 10. A light-emitting diode claimed in any one of Claims 1 to 9,
wherein the substrate is formed of a transparent substrate transparent
to color emitted by the light-emitting diode chip.

11. A method for manufacturing a light-emitting diode comprising
10 mounting, on a surface of a printed substrate, a light-emitting diode
chip having a substrate, a semiconductor layer which is laminated on a
surface of the substrate, is formed of an N-type semiconductor layer
and a P-type semiconductor layer and has a light-emitting portion in
the vicinity of a PN junction surface between the N-type and P-type
15 semiconductor layers, a pair of electrodes for applying voltage to the
semiconductor layer, and a light reflection layer reflecting light emitted
from the light-emitting portion ,thereby obtaining the light-emitting
diode, the method comprising, for mounting the light-emitting diode
chip on the printed substrate,
20 the step of forming beforehand the light reflecting layer on a
front surface or a back surface of the substrate of the light-emitting
diode chip or in the light-emitting diode chip in such a manner that the
light reflecting layer is approximately parallel to the PN junction surface,
and

the step of fixing the obtained light-emitting diode chip on the printed substrate so that the PN junction surface is perpendicular to the surface of the spring substrate and electrically connecting the pair of electrodes of the light-emitting diode chip to the printed substrate.

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